

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2373	PRIORITY SERIAL NO. 10/261,735		
<b>LIST OF ART CITED BY APPLICANT</b> (Use several sheets if necessary)				APPLICANT Garro J. Derderian			
				PRIORITY FILING DATE September 30, 2002		PRIORITY GROUP 1762	
<b>U.S. PATENT DOCUMENTS</b>							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
7	AA	5,270,247	12/1993	Sakuma et al	—	—	
7	AB	6,270,572	08/2001	Kim et al	—	—	
7	AC	6,083,832	07/2000	Sugai	—	—	
7	AD	4,388,105	01/1983	Caldwell et al	—	—	
7	AE	4,831,003	05/1989	Lang et al	—	—	
7	AF	6,287,965	09/2001	Kang et al	—	—	
7	AG	5,480,818	01/1998	Matsumoto et al	—	—	
7	AH	6,203,613	03/2001	Gates et al	—	—	
7	AI	6,174,377	01/2001	Doering et al	—	—	
7	AJ	5,916,365	06/1999	Sherman	—	—	
7	AK	6,335,561	<del>03/2000</del> 1/2002	Sandhu Imoto	—	—	
	AL						
<b>FOREIGN PATENT DOCUMENTS</b>							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
7	AM	EP 0794568	10/1997	Europe	—	—	
7	AN	05-251339	09/1993	Japan	—	—	
	AO						
	AP						
	AQ						
<b>OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)</b>							
7	AR	Kiyoko et al., Patent Abstract Application No. 04-024917 (JP 9224917, 09/1993), "Semiconductor Substrate and its Manufacture."					
7	AS	Ritala, et al., "Atomic Layer Epitaxy - A Valuable Tool for Nanotechnology?" Nanotechnology, Vol. 10, No. 1, pps. 19-24, March 1999.					
7	AT	George, et al., "Surface Chemistry for Atomic Layer Growth", Journal of Physical Chemistry, Vol. 100, No. 31, pps. 13121-13131, August 1, 1996.					
7	AU	Suntola, "Atomic Layer Epitaxy", Handbook of Crystal Growth, Vol. 3, Chapter 14, pps. 602-663.					
7	AV	Vernon, S.M., "Low-cost, high-efficiency solar cells utilizing GaAs-on-Si technology." Dialog Abstract of Report No. NREL/TP-451-5353; 04/1993.					
EXAMINER		Michael Barr					
		DATE CONSIDERED 2/19/04					
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. M122-2373		PRIORITY SERIAL NO. 10/261,735	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Garo J. Derderian			
					PRIORITY FILING DATE September 30, 2002		PRIORITY GROUP 1762	
U.S. PATENT DOCUMENTS								
*Examiner Initial	Class	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
7	AA	4,913,090	04/1990	Harada et al	—	—		
7	AB	6,307,184	10/2001	Womack et al	—	—		
7	AC	5,616,208	04/1997	Lee	—	—		
7	AD	6,203,619	03/2001	McMillan	—	—		
7	AE	5,462,603	10/1995	Murakami	—	—		
7	AF	6,399,921	08/2002	Johnsgard et al	—	—		
7	AG	5,997,588	12/1999	Goodwin et al	—	—		
7	AH	3,785,853	01/1974	Kirkman et al	—	—		
7	AI	6,139,695	10/2000	Washburn et al	—	—		
7	AJ	6,355,561	03/2002	Sandhu et al	—	—		
7	AK	6,335,561	01/2002	Imoto	—	—		
	AL							
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
7	AR		Suntola, "Surface Chemistry of Materials Deposition at Atomic Layer Level", Applied Surface Science, vol. 100/101, March 1998, pp. 391-398.					
7	AS		Aarik et al, "Effect of Growth Conditions on Formation of TiO2-II Thin Films in Atomic Layer Deposition Process", Journal of Crystal Growth, Vol. 181, August 1997, pp. 259-264.					
7	AT		Skarp, "ALE-Reactor for Large Area Depositions", Applied Surface Science, vol. 112, March 1997, pp. 251-254.					
EXAMINER				DATE CONSIDERED				
Michael Barr				2/19/04				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2373	PRIORITY SERIAL NO. 10761,735	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Garo J. Dardarian		
				PRIORITY FILING DATE September 30, 2002	PRIORITY GROUP 1762	
U.S. PATENT DOCUMENTS						
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
7	AA	09/852,533	Sandhu	—	—	08/2000
7	AB	09/843,004	Mercaldi	—	—	08/2000
7	AC	09/927,230	Doan	—	—	08/2001
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					
FOREIGN PATENT DOCUMENTS						
	Document Number	Date	Country	Class	Subclass	Translation
						Yes No
	AM					
	AN					
	AO					
	AP					
	AQ					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)						
	AR					
	AS					
	AT					
EXAMINER			DATE CONSIDERED			
Michael Barr			2/19/04			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>						

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2373	PRIORITY SERIAL NO. 10/261,735			
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Garo J. Derderian				
				PRIORITY FILING DATE September 30, 2002	PRIORITY GROUP 1762			
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
7	AA	6,479,902	11/2002	Lopatin et al	—	—		
7	AB	6,458,416	10/2002	Derderian et al	—	—		
7	AC	6,368,954	04/2002	Lopatin et al	—	—		
7	AD	6,235,571	05/2001	Doan	—	—		
7	AE	6,066,358	05/2000	Guo	—	—		
7	AF	5,366,953	11/1994	Char et al	—	—		
7	AG	5,273,930	12/1993	Steele et al	—	—		
7	AH	2002/0125516	09/2002	Marsh et al	—	—		
	AI							
	AJ							
	AK							
	AL							
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
7	AP		Aarik, et al, "Control of Thin Film Structure by Reactant Pressure in Atomic Layer Deposition of TiO <sub>2</sub> ," Journal of Crystal Growth, 169 (1996) pgs. 496-502					
	AQ							
	AR							
EXAMINER		Michael Barr			DATE CONSIDERED 2/19/04			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								